



ALP-200 Cassette Load Ports

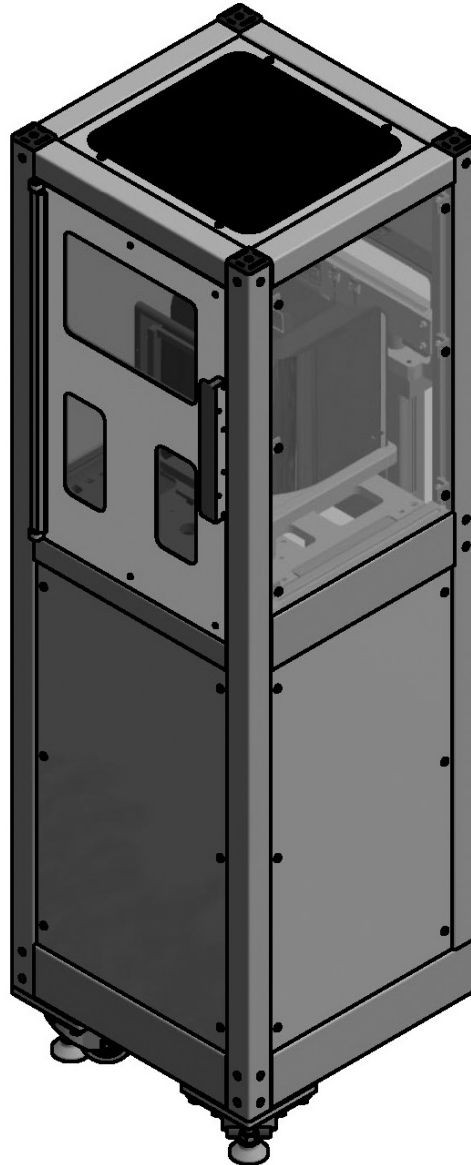
Robotic Components

FEATURES

- Hine Robotics: HAtm-5.0 Atmospheric Elevator
- High reliability of > 3 million MCBF
- Handles wafer sizes up to 200mm
- Sophisticated automation features including wafer mapping, wafer cross-slot detection
- Safety interlocks
- Atmospheric compatibility
- RS-232 / Ethernet control interface
- Valve door

OPTIONS

- 25 or 50 wafer cassettes
- Cassette cradles



ALP-200

The ALP-200 is an atmospheric load lock designed to transfer semiconductor substrates loaded in a cassette and become an advanced factory interface that links the wafer fabrication environment with the OEM cluster system. It features one atmospheric elevator, the HAtm-50, advanced material sensors, and safety interlocks. The ALP-200 includes sophisticated automation features such as wafer mapping and wafer cross-slot detection. The ALP-200 can interface with a wide variety of cluster systems and can be customized to fit your unique needs.



Vacuum Cassette Load Ports

Robotic Components

Ø11.000 [279]

	ALP-200	CLP-200	MLP-200
Wafer Sizes	≤200mm*		
Pay Load	34 Kg†		
Axis of motion	Z	Z	N/A
Transfer Height	1100mm		
High Vacuum Configuration	N/A	Available	
Vacuum performance			
Base operating pressure	N/A	<5.00E-06 Torr	<5.00E-06 Torr
Leak Rate	N/A	1.00E-09 scc He/sec	1.00E-09 scc He/sec
Input Power	24VDC @ 5 Amps		
Cassette type	SEMI Standard Cassettes (≤200mm)		Custom 4 wafer cassette
Materials Exposed	6061-T6 Aluminum, Stainless Steel 300 and 400 Series, Viton, Borosilicate Glass		
Mounting	200mm MESC Slit Valve Support Frame as Required		
Max. Operating Temperature	100°C		
Repeatability			
Vertical Travel	0.10mm **		N/A
Speed			
Vertical Travel	185mm		N/A
Cassette Mapping time	10 seconds		N/A
MTBF	>3.00E+06		N/A

* Hine Automation offers cassette cradle for SEMI standard sizes up to 200mm. Other sizes are available upon request.

† Payload with standard configuration

** Measured as three standard deviations (3σ)

CONNECTOR
PANEL